

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

**OFFICIAL**

<b>Transmittal for Information Disclosure Statement</b>  <b>By Fax</b>	Application Number:	10/758932
	Filing Date	01/16/2004
	First Named Inventor	Marinero
	Group Art Unit	NA
	Examiner	NA
	Atty. Docket Num.	SJO919990025US2

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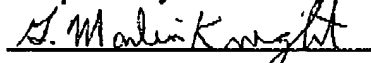
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Commissioner for Patents

By Fax to 703-872-9306

There is no fee due with this Information Disclosure Statement, since it is being filed before the first Office Action. This case is a divisional of 09/955,911 which has issued as 6709774. The Examiner is requested to use the copies of prior art journal articles in the file which are cited below.

Respectfully Submitted,



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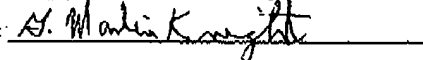
209-295-1982

**FAX Transmission CERTIFICATE**

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**Foreign Patent Documents**

Examiner Initials	Cite No.	Foreign Patent Document		Name of Patentee or Applicant	Publication Date mm-yyyy	Pages, columns, lines where relevant information appears
		Off.	Number Kind Code			
	JP1	JP	JP 62092847 A1	Maeno, et al.	10-1988	

**OTHER PRIOR ART - NON-PATENT LITERATURE**

Examiner Initials	Cite No.	Citation: Author (in capital letters), title, book, symposium, etc.	T
	AA	Cuomo, Gambino and Rosenberg. "The influence of bias on the deposition of metallic films in rf and dc sputtering", J. Vac. Sci. Technology, vol. 11, No. 1, Jan./Feb. 1974, XP002218313, pp. 34-40.	
	BB	A. Moje, European Patent Office, International Search Report for related application PCT/GB 02/03800.	
	CC	N. Tani, "Increase of Coercive Force in Sputtered Hard Disk", IEEE Transactions on Magnetics, vol. 26, No. 4, Jul. 1990, pp. 1282ff.	
	DD	J. Pressesky, et al., "Crystallography and Magnetic Properties of CoCrTa Films Prepared on Cr Underlayers with Different Substrate Bias Conditions", J. Appl. Physics 69(8). Apr. 15, 1991.	
	EE	H. Murata, et al., "Magnetic Properties and Microstructure of CoCrTa/Cr Magnetic Recording Media", Magnetic & Electronic Materials Research Laboratory, Hitachi Metals, Ltd.; vol. 16, No. 3, 1992, pp. 541ff.	
	FF	S. Parkin, "The magic of magnetic multilayers"; IBM Journal of Research & Development; vol. 42, No. 1, 0018-8646/98, Jan. 26, 1998.	
	GG	S. Rossmagel, "Sputter deposition for semiconductor manufacturing"; IBM Journal of Research & Development; vol. 43, No. 1, Mar. 20, 1998.	
	HH	M. Datta, "Applications of electrochemical microfabrication: An Introduction"; IBM Journal of Research & Development; vol. 42, No. 5, 0018-8646/98, Jun. 25, 1998.	

Examiner Signature		Date Considered	
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### U.S. Patent Documents

Examiner Initials	Cite No.	U.S. Patent Document Number	Kind Code	Name of Patentee or Applicant	Publication Date mm-yyyy	Pages, columns, lines where relevant information appears
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Examiner Signature	.....	Date Considered	
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Sheet 1 of 2